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Amendments to the Specification

Please amend the specification as follows. Applicant submits that the amendments made to the specification were made to correct typographical errors and that no new matter has been added to the specification.

On page 1, after the title, please delete the paragraph reading:

—RELATED APPLICATION DATA

The present invention is a 371 of PCT/JP04/05269 filed on 04/13/2004

Please amend the abstract to read as follows:

~~It is an object of the present invention to provide a beam splitter providing a high contrast image and preventing light from scattering, and a laser scanning microscope provided with the above, in which there is provided a high quality probe coming in contact with an electrode pad of a semiconductor device, in which a foreign substance is not likely to attach, a configuration is not likely changed and a preferable electrical contact can be maintained for a long time.~~

According to the present invention an embodiment, a probe coming into contact with an electrode pad of a measurement object comprises a connection terminal part integrally formed and connected to a substrate, a contact part having a tapered configuration, and a supporting part which supports the contact part. The contact part extending from an end of the supporting part has a sectional configuration which shares at least one side face with the supporting part.